

Appl. No. : 09/779,397  
Filed : February 7, 2001

AMENDMENT TO THE CLAIMS

Please amend Claims 1-4 and 9, and cancel Claims 8, 28-31, and 51-59, without prejudice, as follows:

1. (Currently amended) A thermal chemical vapor deposition process for depositing a Si-containing material on a surface, comprising

providing a chemical vapor deposition chamber having disposed therein a substrate,

introducing a gas to said chamber, wherein said gas is comprised of a chemical precursor ~~selected from the group consisting of a compound containing at least one silicon atom and at least one carbon atom and a compound containing at least one carbon atom and at least one oxygen atom,~~

depositing a Si-containing film onto said substrate by thermal chemical vapor deposition, wherein said Si-containing film has a dielectric constant of less than 3.0, as deposited, and

wherein said chemical precursor is selected from the group consisting of siloxanes of the formula  $(R_3Si)_2O$  where each R is independently H, D, F, methyl, ethyl or propyl,

(fluoroalkyl)fluorosiloxanes of the formula  $[(R_f)_{3-x-y}R^1_xF_y]Si_2O$  where  $R_f$  is a perfluoromethyl, perfluoroethyl or perfluoropropyl group,  $R^1$  is H or D, x is 0 or 1, y is 1 or 2, and  $x + y = 1$  or 2,

(fluoroalkyl)silanes of the formula  $(R_f)_4SiR^1_a$  where  $R_f$  is a perfluoromethyl, perfluoroethyl or perfluoropropyl group,  $R^1$  is H or D, and a is 0, 1, 2, or 3,

(alkyl)fluorosilanes of the formula  $R^2_{4-b}SiF_b$  where  $R^2$  is methyl, ethyl or propyl, and b is 1, 2, or 3,

(fluoroalkyl)fluorosilanes of the formula  $(R_f)_{4-c-b}SiR^1_cF_b$  where  $R_f$  is a perfluoromethyl, perfluoroethyl or perfluoropropyl group,  $R^1$  is H or D, c is 0, 1, or 2, b is 1, 2, or 3, and  $c + b = 1, 2, \text{ or } 3,$

alkylsiloxysilanes of the formula  $(R_3SiO)_{4-b}SiR_b$  where each R is independently H, D, F, methyl, ethyl or propyl, and b is 1, 2 or 3,

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alkoxysilanes of the formula  $(R^2O)_{4-a}SiR^1_a$  where  $R^2$  is methyl, ethyl or propyl,  $R^1$  is H or D, and a is 0, 1, 2, or 3,

alkylalkoxysilanes of the formula  $(R^2O)_{4-c-b}SiR^2_bR^1_c$  where each  $R^2$  is independently methyl, ethyl or propyl,  $R^1$  is H or D, c is 0, 1, or 2, b is 1, 2, or 3, and  $c + b = 1, 2, \text{ or } 3$ ,

silylmethanes of the formula  $(H_3Si)_{4-a}CR^1_a$  where  $R^1$  is H or D, and a is 0, 1, 2, or 3,

alkoxysilylmethanes of the formula  $(R^2O)_{4-c-b}(H_3Si)_bCR^1_c$  where  $R^2$  is methyl, ethyl or propyl,  $R^1$  is H or D, c is 0, 1, or 2, b is 1, 2, or 3, and  $c + b = 1, 2, \text{ or } 3$ ,

alkylalkoxysilylmethanes of the formula  $(R^2O)_{4-x-y-z}R^2_z(H_3Si)_yCR^1_x$  where each  $R^2$  is independently methyl, ethyl or propyl,  $R^1$  is H or D, x is 0 or 1, y is 1 or 2, z is 1 or 2, and  $x + y + z = 2 \text{ or } 3$ ,

alkoxymethanes of the formula  $(R^3O)_{4-a}CR^1_a$  where  $R^3$  is methyl, ethyl, propyl, or t-butyl,  $R^1$  is H or D, and a is 0, 1, 2, or 3,

alkylalkoxymethanes of the formula  $(R^3O)_{4-c-b}R^2_bCR^1_c$  where  $R^3$  is methyl, ethyl, propyl, or t-butyl,  $R^2$  is methyl, ethyl or propyl,  $R^1$  is H or D, c is 0, 1, or 2, b is 1, 2, or 3, and  $c + b = 1, 2, \text{ or } 3$ ,

and mixtures thereof.

2. (Currently amended) The thermal chemical vapor deposition process of Claim 1 wherein said Si-containing film is deposited onto said substrate at a temperature is-greater than about 300°C.

3. (Currently amended) The thermal chemical vapor deposition process of Claim 1 wherein said Si-containing film is deposited onto said substrate at a temperature is-in the range of about 350°C to about 700°C.

4. (Currently amended) The thermal chemical vapor deposition process of Claim 1 wherein said Si-containing film is deposited onto said substrate at a temperature is-in the range of about 400°C to about 550°C.

5. (Original) The thermal chemical vapor deposition process of Claim 1 wherein said Si-containing film has a dielectric constant of about 2.7 or lower.

6. (Original) The thermal chemical vapor deposition process of Claim 1 wherein said Si-containing film has a dielectric constant of about 2.5 or lower.

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7. (Original) The thermal chemical vapor deposition process of Claim 1 wherein said gas does not contain an oxidizing agent.

8. (Canceled)

9. (Currently amended) The thermal chemical vapor deposition process of Claim 8 1 wherein said ~~first~~ chemical precursor is selected from the group consisting of

a siloxane of the formula  $(H_3Si)_2O$ ,

a siloxane of the formula  $(R_3Si)_2O$  in which at least one R is F,

a siloxane of the formula  $(R_3Si)_2O$  in which at least one R is methyl or ethyl,

a (fluoroalkyl)fluorosiloxane of the formula  $[(R_f)_{3-x-y}R^1_xF_y]_2Si_2O$  in which  $R_f$  is trifluoromethyl,

a (fluoroalkyl)silane of the formula  $(R_f)_{4-a}SiR^1_a$  in which  $R_f$  is trifluoromethyl,

an (alkyl)fluorosilane of the formula  $R^2_{4-b}SiF_b$  in which  $R^2$  is methyl or ethyl,

a (fluoroalkyl)fluorosilane of the formula  $(R_f)_{4-c-b}SiR^1_cF_b$  in which  $R_f$  is trifluoromethyl,

an alkylsiloxysilane of the formula  $(R_3SiO)_{4-b}SiR_b$  in which each R is independently H, D, methyl, or ethyl,

an alkoxysilane of the formula  $(R^2O)_{4-a}SiR^1_a$  in which  $R^2$  is methyl or ethyl,

an alkylalkoxysilane of the formula  $(R^2O)_{4-c-b}SiR^2_bR^1_c$  in which each  $R^2$  is independently methyl or ethyl,

an alkoxysilylmethane of the formula  $(R^2O)_{4-c-b}(H_3Si)_bCR^1_c$  in which  $R^2$  is methyl or ethyl, and

an alkylalkoxysilylmethane of the formula  $(R^2O)_{4-x-y-z}R^2_z(H_3Si)_yCR^1_x$  in which each  $R^2$  is independently methyl or ethyl.

10. (Original) A thermal chemical vapor deposition process for depositing a Si-containing material on a surface, comprising

providing a chemical vapor deposition chamber having disposed therein a substrate,

introducing a gas to said chamber, wherein said gas is comprised of a first chemical precursor selected from the group consisting of

siloxanes of the formula  $(R_3Si)_2O$  where each R is independently H, D, F, methyl, ethyl or propyl,

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(fluoroalkyl)fluorosiloxanes of the formula  $[(R_f)_{3-x-y}R^1_xF_y]_2SiO$  where  $R_f$  is a perfluoromethyl, perfluoroethyl or perfluoropropyl group,  $R^1$  is H or D,  $x$  is 0 or 1,  $y$  is 1 or 2, and  $x + y = 1$  or 2,

(fluoroalkyl)silanes of the formula  $(R_f)_{4-a}SiR^1_a$  where  $R_f$  is a perfluoromethyl, perfluoroethyl or perfluoropropyl group,  $R^1$  is H or D, and  $a$  is 0, 1, 2, or 3,

(alkyl)fluorosilanes of the formula  $R^2_{4-b}SiF_b$  where  $R^2$  is methyl, ethyl or propyl, and  $b$  is 1, 2, or 3,

(fluoroalkyl)fluorosilanes of the formula  $(R_f)_{4-c-b}SiR^1_cF_b$  where  $R_f$  is a perfluoromethyl, perfluoroethyl or perfluoropropyl group,  $R^1$  is H or D,  $c$  is 0, 1, or 2,  $b$  is 1, 2, or 3, and  $c + b = 1, 2$ , or 3,

alkylsiloxysilanes of the formula  $(R_3SiO)_{4-b}SiR_b$  where each  $R$  is independently H, D, F, methyl, ethyl or propyl, and  $b$  is 1, 2 or 3,

alkoxysilanes of the formula  $(R^2O)_{4-a}SiR^1_a$  where  $R^2$  is methyl, ethyl or propyl,  $R^1$  is H or D, and  $a$  is 0, 1, 2, or 3,

alkylalkoxysilanes of the formula  $(R^2O)_{4-c-b}SiR^2_bR^1_c$  where each  $R^2$  is independently methyl, ethyl or propyl,  $R^1$  is H or D,  $c$  is 0, 1, or 2,  $b$  is 1, 2, or 3, and  $c + b = 1, 2$ , or 3,

silylmethanes of the formula  $(H_3Si)_{4-a}CR^1_a$  where  $R^1$  is H or D, and  $a$  is 0, 1, 2, or 3,

alkoxysilylmethanes of the formula  $(R^2O)_{4-c-b}(H_3Si)_bCR^1_c$  where  $R^2$  is methyl, ethyl or propyl,  $R^1$  is H or D,  $c$  is 0, 1, or 2,  $b$  is 1, 2, or 3, and  $c + b = 1, 2$ , or 3,

alkylalkoxysilylmethanes of the formula  $(R^2O)_{4-x-y-z}R^2_z(H_3Si)_yCR^1_x$  where each  $R^2$  is independently methyl, ethyl or propyl,  $R^1$  is H or D,  $x$  is 0 or 1,  $y$  is 1 or 2,  $z$  is 1 or 2, and  $x + y + z = 2$  or 3,

alkoxymethanes of the formula  $(R^3O)_{4-a}CR^1_a$  where  $R^3$  is methyl, ethyl, propyl, or t-butyl,  $R^1$  is H or D, and  $a$  is 0, 1, 2, or 3,

alkylalkoxymethanes of the formula  $(R^3O)_{4-c-b}R^2_bCR^1_c$  where  $R^3$  is methyl, ethyl, propyl, or t-butyl,  $R^2$  is methyl, ethyl or propyl,  $R^1$  is H or D,  $c$  is 0, 1, or 2,  $b$  is 1, 2, or 3, and  $c + b = 1, 2$ , or 3,

and mixtures thereof;

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and depositing a Si-containing film onto said substrate by thermal chemical vapor deposition at a temperature of about 300°C or higher, wherein said Si-containing film has a dielectric constant of about 3.5 or lower, as deposited.

11. (Original) The thermal chemical vapor deposition process of Claim 10 wherein said first chemical precursor is selected from the group consisting of

- a siloxane of the formula  $(\text{H}_3\text{Si})_2\text{O}$ ,
- a siloxane of the formula  $(\text{R}_3\text{Si})_2\text{O}$  in which at least one R is F,
- a siloxane of the formula  $(\text{R}_3\text{Si})_2\text{O}$  in which at least one R is methyl or ethyl,
- a (fluoroalkyl)fluorosiloxane of the formula  $[(\text{R}_f)_{3-x-y}\text{R}^1_x\text{F}_y]\text{Si}]_2\text{O}$  in which  $\text{R}_f$  is trifluoromethyl,
- a (fluoroalkyl)silane of the formula  $(\text{R}_f)_4\text{SiR}^1_a$  in which  $\text{R}_f$  is trifluoromethyl,
- an (alkyl)fluorosilane of the formula  $\text{R}^2_{4-b}\text{SiF}_b$  in which  $\text{R}^2$  is methyl or ethyl,
- a (fluoroalkyl)fluorosilane of the formula  $(\text{R}_f)_{4-c-b}\text{SiR}^1_c\text{F}_b$  in which  $\text{R}_f$  is trifluoromethyl,
- an alkylsiloxysilane of the formula  $(\text{R}_3\text{SiO})_{4-b}\text{SiR}_b$  in which each R is independently H, D, methyl, or ethyl,
- an alkoxysilane of the formula  $(\text{R}^2\text{O})_{4-a}\text{SiR}^1_a$  in which  $\text{R}^2$  is methyl or ethyl,
- an alkylalkoxysilane of the formula  $(\text{R}^2\text{O})_{4-c-b}\text{SiR}^2_b\text{R}^1_c$  in which each  $\text{R}^2$  is independently methyl or ethyl,
- an alkoxysilylmethane of the formula  $(\text{R}^2\text{O})_{4-c-b}(\text{H}_3\text{Si})_b\text{CR}^1_c$  in which  $\text{R}^2$  is methyl or ethyl, and
- an alkylalkoxysilylmethane of the formula  $(\text{R}^2\text{O})_{4-x-y-z}\text{R}^2_z(\text{H}_3\text{Si})_y\text{CR}^1_x$  in which each  $\text{R}^2$  is independently methyl or ethyl.

12. (Original) The thermal chemical vapor deposition process of Claim 10 wherein said gas is further comprised of a second chemical precursor selected from the group consisting of silane, disilane, trisilane, methane, ethane, propane, butane, oxygen, ozone, hydrogen peroxide, nitrous oxide and water.

13. (Original) The thermal chemical vapor deposition process of Claim 10 wherein said temperature is in the range of about 350°C to about 700°C.

14. (Original) The thermal chemical vapor deposition process of Claim 10 wherein said temperature is in the range of about 400°C to about 550°C.

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15. (Original) The thermal chemical vapor deposition process of Claim 10 wherein said Si-containing film has a dielectric constant of about 3.0 or lower.

16. (Original) The thermal chemical vapor deposition process of Claim 10 wherein said Si-containing film has a dielectric constant of about 2.7 or lower.

17. (Original) The thermal chemical vapor deposition process of Claim 10 wherein said Si-containing film has a dielectric constant of about 2.5 or lower.

18. (Original) A chemical vapor deposition process for depositing a Si-containing material on a surface, comprising

providing a chemical vapor deposition chamber having disposed therein a substrate;

introducing a gas to said chamber, wherein said gas is comprised of a first chemical precursor selected from the group consisting of

silylmethanes of the formula  $(\text{H}_3\text{Si})_{4-a}\text{CR}^1_a$  where  $\text{R}^1$  is H or D, and a is 0, 1, 2, or 3,

alkoxysilylmethanes of the formula  $(\text{R}^2\text{O})_{4-c-b}(\text{H}_3\text{Si})_b\text{CR}^1_c$  where  $\text{R}^2$  is methyl, ethyl or propyl,  $\text{R}^1$  is H or D, c is 0, 1, or 2, b is 1, 2, or 3, and  $c + b = 1, 2, \text{ or } 3$ ,

alkylalkoxysilylmethanes of the formula  $(\text{R}^2\text{O})_{4-x-y-z}\text{R}^2_z(\text{H}_3\text{Si})_y\text{CR}^1_x$  where each  $\text{R}^2$  is independently methyl, ethyl or propyl,  $\text{R}^1$  is H or D, x is 0 or 1, y is 1 or 2, z is 1 or 2, and  $x + y + z = 2 \text{ or } 3$ ,

alkoxymethanes of the formula  $(\text{R}^3\text{O})_{4-a}\text{CR}^1_a$  where  $\text{R}^3$  is methyl, ethyl, propyl, or t-butyl,  $\text{R}^1$  is H or D, and a is 0, 1, 2, or 3,

alkylalkoxymethanes of the formula  $(\text{R}^3\text{O})_{4-c-b}\text{R}^2_b\text{CR}^1_c$  where  $\text{R}^3$  is methyl, ethyl, propyl, or t-butyl,  $\text{R}^2$  is methyl, ethyl or propyl,  $\text{R}^1$  is H or D, c is 0, 1, or 2, b is 1, 2, or 3, and  $c + b = 1, 2, \text{ or } 3$ ,

and mixtures thereof, and

depositing a Si-containing film onto said substrate, wherein said Si-containing film has a dielectric constant of about 3.5 or lower, as deposited.

19. (Original) The chemical vapor deposition process of Claim 18 wherein said Si-containing film is deposited by thermal chemical vapor deposition at a temperature of about 300°C or higher.

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20. (Original) The chemical vapor deposition process of Claim 19 wherein said temperature is in the range of about 350°C to about 700°C.

21. (Original) The chemical vapor deposition process of Claim 19 wherein said temperature is in the range of about 400°C to about 550°C.

22. (Original) The chemical vapor deposition process of Claim 18 wherein said first chemical precursor is selected from the group consisting of

an alkoxysilylmethane of the formula  $(R^2O)_{4-c-b}(H_3Si)_bCR^1_c$  in which  $R^2$  is methyl or ethyl, and

an alkylalkoxysilylmethane of the formula  $(R^2O)_{4-x-y-z}R^2_x(H_3Si)_yCR^1_x$  in which each  $R^2$  is independently methyl or ethyl.

23. (Original) The chemical vapor deposition process of Claim 18 wherein said first chemical precursor is tetrasilylmethane.

24. (Original) The chemical vapor deposition process of Claim 18 wherein said gas is further comprised of a second chemical precursor selected from the group consisting of silane, disilane, trisilane, methane, ethane, propane, butane, oxygen, ozone, hydrogen peroxide, nitrous oxide and water.

25. (Original) The thermal chemical vapor deposition process of Claim 18 wherein said Si-containing film has a dielectric constant of about 3.0 or lower.

26. (Original) The chemical vapor deposition process of Claim 18 wherein said Si-containing film has a dielectric constant of about 2.7 or lower.

27. (Original) The chemical vapor deposition process of Claim 18 wherein said Si-containing film has a dielectric constant of about 2.5 or lower.

28. (Canceled)

29. (Canceled)

30. (Canceled)

31. (Canceled)

32. (Original) A chemical vapor deposition process for depositing a Si-containing material on a surface, comprising

providing a chemical vapor deposition chamber having disposed therein a substrate;

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introducing a first gas to said chamber, wherein said first gas is comprised of a first chemical precursor,

depositing a first Si-containing film onto said substrate, wherein said first Si-containing film has a dielectric constant of about 3.5 or lower, as deposited, and wherein said first Si-containing film has a thickness in the range of about 50Å to about 5000Å,

introducing a second gas to said chamber, wherein said second gas is comprised of a second chemical precursor different from said first chemical precursor, and

depositing a second Si-containing film onto said first Si-containing film to provide a multi-layered Si-containing film,

wherein said second Si-containing film has a dielectric constant of about 3.5 or lower, as deposited, wherein said second Si-containing film has a thickness in the range of about 50Å to about 5000Å, and wherein said multi-layered Si-containing film has a dielectric constant of about 3.5 or lower, as deposited.

33. (Original) The chemical vapor deposition process of Claim 32 wherein said multi-layered Si-containing film has a dielectric constant of about 3.0 or lower.

34. (Original) The chemical vapor deposition process of Claim 32 wherein said multi-layered Si-containing film has a dielectric constant of about 2.7 or lower.

35. (Original) The chemical vapor deposition process of Claim 32 wherein said multi-layered Si-containing film has a dielectric constant of about 2.5 or lower.

36. The chemical vapor deposition process of Claim 32 wherein said first Si-containing film is deposited by thermal chemical vapor deposition at a temperature of about 300°C or higher.

37. (Original) The chemical vapor deposition process of Claim 36 wherein said temperature is in the range of about 350°C to about 700°C.

38. (Original) The chemical vapor deposition process of Claim 36 wherein said temperature is in the range of about 400°C to about 550°C.

39. (Original) The chemical vapor deposition process of Claim 32 wherein said first chemical precursor is selected from the group consisting of

siloxanes of the formula  $(R_3Si)_2O$  where each R is independently H, D, F, methyl, ethyl or propyl,



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(fluoroalkyl)fluorosiloxanes of the formula  $[(R_f)_{3-x-y}R^1_xF_y]Si_2O$  where  $R_f$  is a perfluoromethyl, perfluoroethyl or perfluoropropyl group,  $R^1$  is H or D, x is 0 or 1, y is 1 or 2, and  $x + y = 1$  or 2,

(fluoroalkyl)silanes of the formula  $(R_f)_{4-a}SiR^1_a$  where  $R_f$  is a perfluoromethyl, perfluoroethyl or perfluoropropyl group,  $R^1$  is H or D, and a is 0, 1, 2, or 3,

(alkyl)fluorosilanes of the formula  $R^2_{4-b}SiF_b$  where  $R^2$  is methyl, ethyl or propyl, and b is 1, 2, or 3,

(fluoroalkyl)fluorosilanes of the formula  $(R_f)_{4-c-b}SiR^1_cF_b$  where  $R_f$  is a perfluoromethyl, perfluoroethyl or perfluoropropyl group,  $R^1$  is H or D, c is 0, 1, or 2, b is 1, 2, or 3, and  $c + b = 1, 2, \text{ or } 3$ ,

alkylsiloxysilanes of the formula  $(R_3SiO)_{4-b}SiR_b$  where each R is independently H, D, F, methyl, ethyl or propyl, and b is 1, 2 or 3,

alkoxysilanes of the formula  $(R^2O)_{4-a}SiR^1_a$  where  $R^2$  is methyl, ethyl or propyl,  $R^1$  is H or D, and a is 0, 1, 2, or 3,

alkylalkoxysilanes of the formula  $(R^2O)_{4-c-b}SiR^2_bR^1_c$  where each  $R^2$  is independently methyl, ethyl or propyl,  $R^1$  is H or D, c is 0, 1, or 2, b is 1, 2, or 3, and  $c + b = 1, 2, \text{ or } 3$ ,

silylmethanes of the formula  $(H_3Si)_{4-a}CR^1_a$  where  $R^1$  is H or D, and a is 0, 1, 2, or 3,

alkoxysilylmethanes of the formula  $(R^2O)_{4-c-b}(H_3Si)_bCR^1_c$  where  $R^2$  is methyl, ethyl or propyl,  $R^1$  is H or D, c is 0, 1, or 2, b is 1, 2, or 3, and  $c + b = 1, 2, \text{ or } 3$ ,

alkylalkoxysilylmethanes of the formula  $(R^2O)_{4-x-y-z}R^2_z(H_3Si)_yCR^1_x$  where each  $R^2$  is independently methyl, ethyl or propyl,  $R^1$  is H or D, x is 0 or 1, y is 1 or 2, z is 1 or 2, and  $x + y + z = 2$  or 3,

alkoxymethanes of the formula  $(R^3O)_{4-a}CR^1_a$  where  $R^3$  is methyl, ethyl, propyl, or t-butyl,  $R^1$  is H or D, and a is 0, 1, 2, or 3,

alkylalkoxymethanes of the formula  $(R^3O)_{4-c-b}R^2_bCR^1_c$  where  $R^3$  is methyl, ethyl, propyl, or t-butyl,  $R^2$  is methyl, ethyl or propyl,  $R^1$  is H or D, c is 0, 1, or 2, b is 1, 2, or 3, and  $c + b = 1, 2, \text{ or } 3$ ,

and mixtures thereof.

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40. (Original) The chemical vapor deposition process of Claim 32 wherein said second chemical precursor contains Si and C.

41. (Original) The chemical vapor deposition process of Claim 32 wherein said second gas is further comprised of a third chemical precursor selected from the group consisting of silane, disilane, trisilane, methane, ethane, propane, butane, oxygen, ozone, hydrogen peroxide, nitrous oxide and water.

42. (Original) The chemical vapor deposition process of Claim 32 wherein said first Si-containing film and said second Si-containing film each independently have a thickness in the range of about 150Å to about 2500Å.

43. (Original) The chemical vapor deposition process of Claim 32 which further comprises

introducing a third gas to said chamber, wherein said third gas is comprised of a third chemical precursor different from said second chemical precursor, and

depositing a third Si-containing film onto said second Si-containing film to provide a multi-layered Si-containing film having at least three layers, wherein said third Si-containing film has a dielectric constant of about 3.5 or lower, as deposited, and wherein said third Si-containing film has a thickness in the range of about 50Å to about 5000Å.

44. (Original) The chemical vapor deposition process of Claim 43 wherein said multi-layered Si-containing film having at least three layers has a dielectric constant of about 3.0 or lower.

45. (Original) The chemical vapor deposition process of Claim 43 wherein said multi-layered Si-containing film having at least three layers has a dielectric constant of about 2.7 or lower.

46. (Original) The chemical vapor deposition process of Claim 43 wherein said multi-layered Si-containing film having at least three layers has a dielectric constant of about 2.5 or lower.

47. (Original) The chemical vapor deposition process of Claim 43 wherein said first Si-containing film is deposited by thermal chemical vapor deposition at a temperature of about 300°C or higher.

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48. (Original) The chemical vapor deposition process of Claim 47 wherein said temperature is in the range of about 350°C to about 700°C.

49. (Original) The chemical vapor deposition process of Claim 47 wherein said temperature is in the range of about 400°C to about 550°C.

50. (Original) The chemical vapor deposition process of Claim 43 wherein said first Si-containing film, said second Si-containing film and said third Si-containing film each independently have a thickness in the range of about 150Å to about 2500Å.

- 51. (Canceled)
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